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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **2812**

Serial No.: **10/517,765**

Examiner: **Not assigned**

Filed: **February 3, 2006**

P.T.O. Confirmation No.: 6791

FOR: **SUBSTRATE TREATING APPARATUS AND METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE**

REQUEST FOR STATUS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: September 1, 2006

Sir:


The undersigned attorney requests the status of the above-identified application.

The application was filed on **February 3, 2006**, in the U.S. Patent and Trademark Office
and to date no Office Action has been received.

In the event any fees are required in connection with this paper, please charge Deposit
Account No. 01-2340.

Respectfully submitted,

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